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Paper No. 8

**OCT 27 2003**

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In Re Application of  
YOSHIROU TSURUGIDA  
Application No. 10/034,379  
Filed: January 3, 2002  
Title: METHOD FOR SELECTIVELY OXIDIZING A SILICON  
WAFER

: Withdrawal From Issue  
:  
:

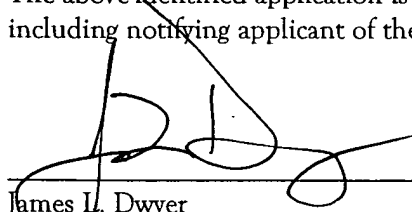
The above-identified application is withdrawn from issue after payment of the issue fee due to unpatentability of one or more claims. See 37 CFR 1.313(b).

The above-identified application is hereby withdrawn from issue.

The issue fee is refundable upon written request. If, however, the application is again found allowable, the issue fee can be applied toward payment of the issue fee in the amount identified on the new Notice of Allowance and Issue Fee Due upon written request. This request and any balance due must be received on or before the due date noted in the new Notice of Allowance in order to prevent abandonment of the application.

Telephone inquiries should be directed to David Nelms at (703) 308-4910.

The above-identified application is being forwarded to the examiner for prompt appropriate action, including notifying applicant of the new status of this application.

  
James L. Dwyer  
Director, Technology Center 2800  
Communications